

Electronic Acknowledgement Receipt

II(w)

EFS ID:	1193633
Application Number:	10598933
Confirmation Number:	2213
Title of Invention:	Semiconductor wafer inspection device and method
First Named Inventor:	Fumi Nabeshima
Customer Number:	44719
Filer:	Joseph Patrick Farrar
Filer Authorized By:	
Attorney Docket Number:	PA214WP002
Receipt Date:	14-SEP-2006
Filing Date:	
Time Stamp:	21:19:36
Application Type:	U.S. National Stage under 35 USC 371
International Application Number:	PCT/JP05/12345

Payment information:

Submitted with Payment	yes
Payment was successfully received in RAM	\$900
RAM confirmation Number	753
Deposit Account	503546

File Listing:

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1	Drawings	fig01-fig06.pdf	494922	no	6
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Information:					
2	Application Data Sheet	ADSKomatsuElec.pdf	412012	no	4
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3	Assignee showing of ownership per 37 CFR 3.73(b).	US_Assignment.pdf	72337	no	1
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5	Transmittal letter	NewUtilityPatentApplication.pdf	41043	no	2
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6		PKM050074PCT_SPEC.pdf	5050056	yes	39
	Multipart Description				
	Doc Desc		Start	End	
	Specification		1	34	
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7	Transmittal letter	sb0005_fillTransmittalFormInitalFiling.pdf	269460	no	2
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IFW

Electronic Patent Application Fee Transmittal

Application Number:

Filing Date:

Adjustment date: 01/18/2008 SDIRETA1
 09/15/2006 INTEFSW 00000753 503546 10598933
 01 FC:1631 300.00 CR
 02 FC:1642 400.00 CR
 03 FC:1633 200.00 CR

Title of Invention: 10598933

Semiconductor wafer inspection device and method

8/2008 SDIRETH1 00000001 503546
 C:1011 300.00 DA
 C:1111 500.00 DA
 C:1311 200.00 DA

First Named Inventor:

Fumi Nabeshima

Filer:

Joseph Patrick Farrar

Attorney Docket Number:

PA214WP002

Filed as Large Entity

U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
National Stage Fee	1631	1	300	300
Natl Stage Search Fee - Report provided	1642	1	400	400
National Stage Exam - all other cases	1633	1	200	200

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

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